

Amendment to the Specification:

On page 11, please replace the paragraph beginning at line 19 with the following amended paragraph:

Figure 6 represents a fifth step of that method[[]].

On page 11, after line 19, please add the following paragraph:

Figure 7 illustrates the silicon plate of Figure 3, having a non-continuous sacrificial layer.

On page 16, please replace the paragraph beginning at line 26 with the following amended paragraph:

It is clear that a non-continuous sacrificial layer 3 may be obtained as shown in Figure 7, for example by localized deposition or by etching; this enables areas already opened up to be defined in the stacked structure.